

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Original) High-repetition mode-coupled ultra-short pulse laser system for generating femto- or picosecond pulses, according to the principle of pulse decoupling, comprising at least

- an amplifying laser medium (11, 11')
- a laser resonator with at least one resonator mirror (6a-d, 7a-g, 8a-i, 16, 14, 14') and at least one pulse decoupling component (1, 1'),
- a saturable absorber mirror (14, 14') and
- a pump source (9, 9'), in particular a laser diode source, for pumping the laser medium (11, 11'),

characterized in that the pulse decoupling component (1, 1') is an electro-optical modulator.

2. (Original) Ultra-short pulse laser system according to Claim 1, characterized in that the electro-optical modulator is a BBO cell.

3. (Original) Ultra-short pulse laser system according to Claim 1, characterized in that the electro-optical modulator is an RTP cell, in particular having a component for compensating a thermal drift.

4. (Currently Amended) Ultra-short pulse laser system according to ~~any of the preceding Claims~~ Claim 1, characterized by at least one dispersive mirror (6a-d, 7a-g, 8a-i) for dispersion compensation, in particular a Gires-Tournois interferometer.

5. (Original) Ultra-short pulse laser system according to Claim 4, characterized in that the laser system is formed so that, in the generation of picosecond pulses, the nonlinear phase is less than 100 mrad, in particular less than 10 mrad, the nonlinear phase being calculated per resonator cycle and per 1% modulation depth of the saturable absorber mirror.

6. (Currently Amended) Ultra-short pulse laser system according to ~~any of the preceding Claims~~Claim 1, characterized in that the laser system is formed so that, in the generation of femtosecond pulses, the r parameter is less than 1, in particular less than 0.25.

7. (Currently Amended) Ultra-short pulse laser system according to ~~any of the preceding Claims~~Claim 1 characterized in that the laser medium (11, 11') is ytterbium-doped glass or Nd:YVO₄.

8. (Currently Amended) Ultra-short pulse laser system according to ~~any of the preceding Claims~~Claim 1, characterized in that the laser medium (11, 11') comprises ytterbium-doped tungstates, in particular Yb:KGW or Yb:KYW.

9. (Currently Amended) Ultra-short pulse laser system according to ~~any of the preceding Claims~~Claim 1, characterized in that the laser medium has a disc-like geometry.

10. (Currently Amended) Ultra-short pulse laser system according to ~~any of the preceding Claims~~Claim 1, characterized in that the pump source is formed and is arranged in such a way that a pump light spot having a ratio of length to width of at least 2:1 is formed, the pump light spot consisting of a single ray or the combination of a plurality of rays, the rays preferably being generated by laser diodes.

11. (Currently Amended) Use of a high-repetition mode-coupled ultra-short pulse laser system according to ~~any of the preceding Claims~~Claim 1 for direct material processing by plasma generation.